

CLEAN COPY OF PENDING CLAIMS

50. (Amended) A method for forming conducting structures separated by gaps on substrate comprising:

providing a substrate and a wiring line layer above the substrate;

forming a cap layer above the wiring line layer, wherein said cap layer has a uniform thickness which is sufficient to reduce reflectivity of light passing through such cap layer;

etching through a portion of the cap layer and portions of the wiring line layer to form wiring lines separated by gaps, the wiring lines having a remaining portion of the cap layer thereon; and

depositing a dielectric material on surfaces exposed by the etching process including exposed surfaces of the cap layer to substantially fill the gaps between the wiring lines, said dielectric material including a layer formed by high density plasma chemical vapor deposition,

wherein the cap layer acts to protect the wiring lines and portions of the cap layer are sacrificially removed during the process of depositing the dielectric material.

51. The method of claim 50, wherein the cap layer is used as a hard mask during etching of the wiring line layer.

52. The method of claim 50, wherein the cap layer comprises an antireflective coating.

53. The method of claim 50, wherein portions of the cap layer are partially etched during the deposition of a dielectric material using high density plasma chemical vapor deposition.

54. The method of claim 50, wherein the cap layer comprises a material selected from the group consisting of silicon oxide, silicon nitride, or oxynitride.

55. The method of claim 50, wherein the remaining portion of the cap layer on at least one wiring line has a rectangular shape in cross section.

56. The method of claim 50, wherein the remaining portion of the cap layer on at least one wiring line has a trapezoidal shape in cross section.

57. The method of claim 56, wherein the trapezoidal shape includes top and bottom surfaces parallel to one another and side surfaces that extend inwardly from the bottom surface to the top surface.

58. The method of claim 50, wherein the remaining portion of the cap layer on at least one wiring line has a triangular shape in cross section.

59. The method of claim 50, wherein the remaining portion of the cap layer on at least one wiring line has, in cross section, a rectangular shape having its upper corners etched away.

60. The method of claim 50, wherein the remaining portion of the cap layer is partially etched and redeposited into the gaps during the high density plasma chemical vapor deposition process.

61. (Amended) A method of forming conducting structures separated by gaps filled with dielectric material, comprising the steps of:

providing a substrate containing silicon, the substrate having a surface;

forming a surface layer comprising at least one material selected from the group consisting of titanium nitride, titanium silicide and a titanium-tungsten alloy, the surface layer disposed on the substrate surface.

forming a metal wiring layer on the surface layer, the metal wiring layer having an upper surface;

forming a protective layer comprising at least one material selected from the group consisting of titanium nitride, titanium silicide and a titanium-tungsten alloy, the protective layer disposed on the upper surface of the metal wiring layer, the protective layer having a top surface;;

forming a cap layer comprising at least one material selected from the

group consisting of an oxide, a nitride, a silicon-rich oxide, and an oxynitride, the cap layer disposed on the top surface of the protective layer, wherein said cap layer has a uniform thickness which is sufficient to reduce reflectivity of light passing through such cap layer;

forming a patterned photoresist layer above the cap layer, said patterned photoresist layer covering selected portions of the cap layer and exposing other portions of the cap layer;

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etching the cap layer, the protective layer and the metal wiring layer to form the conductive structures separated by gaps; and

forming a layer of high density plasma chemical vapor deposition (HDPCVD) dielectric material on surfaces exposed by the etching process including exposed surfaces of the cap layer,

wherein the cap layer acts to protect the wiring lines and portions of the cap layer are sacrificially removed during the process of depositing a dielectric material on surfaces exposed by the etching process.

62. (New) The method of claim 61, wherein the cap layer is used as a hard mask during etching of the wiring line layer.

63. (New) The method of claim 61, wherein portions of the cap layer are partially etched during the deposition of a dielectric material using high density plasma chemical vapor deposition.

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64. (New) The method of claim 61, wherein the cap layer comprises a material selected from the group consisting of silicon oxide, silicon nitride, or oxynitride.

65. (New) The method of claim 61, wherein the layer of dielectric material formed by HDPCVD substantially fills the gaps between the conductive structures.

66. (New) The method of claim 61, wherein the layer of dielectric material formed by HDPCVD is deposited onto a surface of the substrate, onto side surfaces of the metal wiring layer, the surface layer, the protective

layer, and the cap layer.

67. (New) The method of claim 61, wherein the layer of dielectric material formed by HDPCVD is deposited onto an upper surface of the cap layer.

68. (New) The method of claim 61, further comprising removing the patterned photoresist layer prior to forming a layer of high density plasma chemical vapor deposition (HDPCVD) dielectric material.

69. (New) The method of claim 61, wherein the cap layer protects the underlying wiring layer during the process of forming a layer of high density plasma chemical vapor deposition (HDPCVD) dielectric material.

70. (New) The method of claim 61, wherein the protective layer comprises a material having a first dielectric constant and the antireflective coating comprises a material having a second dielectric constant, different from the first dielectric constant.

71. (New) The method of claim 61, wherein the first dielectric constant and the second dielectric constant form a graded index of refraction.

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72. (New) The method of claim 71, wherein the graded index of refraction reduces boundary reflections between the cap layer and the first antireflective coating.

73. (New) The method of claim 61, wherein the antireflective coating of the cap layer reduces reflection by generating destructive interference in reflected light.

74. (New) The method of claim 61, wherein twice the thickness of the cap layer is an odd number of the wavelengths of the exposure light, compensating for the dielectric constant of the cap layer.

75. (New) The method of claim 50, wherein the protective layer comprises a material having a first dielectric constant and the antireflective coating comprises a material having a second dielectric constant, different from the first dielectric constant.

76. (New) The method of claim 50, wherein the first dielectric constant and the second dielectric constant form a graded index of refraction.

77. (New) The method of claim 76, wherein the graded index of refraction reduces boundary reflections between the cap layer and the first antireflective coating.

78. (New) The method of claim 50, wherein the antireflective coating of the cap layer reduces reflection by generating destructive interference in reflected light.

79. (New) The method of claim 61, wherein twice the thickness of the cap layer is an odd number of the wavelengths of the exposure light, compensating for the dielectric constant of the cap layer.

80. (New) A method for forming conducting structures separated by gaps on a substrate comprising:

providing a substrate and a wiring line layer above the substrate;

forming a first antireflective coating above the wiring line layer;

forming a cap layer adapted for protecting the wiring line layer during a plasma based process, the cap layer being situated above the first antireflective coating, wherein the cap layer and the first antireflective coating have different dielectric constants;

etching through portions of the first antireflective coating, a portion of the cap layer and a portion of the wiring line layer to form wiring lines separated by high aspect ratio gaps; and

depositing a dielectric material to substantially fill said gaps, including using a first plasma based process having both a deposition component and an adjustable etching component at least until any high aspect ratio gaps are substantially filled, followed by a second plasma based process that fills any remaining portion of said gaps and results in a planarized surface, and which second plasma based process does not include an adjustable etching

component.

81. (New) The method of claim 80, wherein the first antireflective coating absorbs portions of radiation applied during a lithographic process and the cap layer creates destructive interference with portions of radiation applied during the lithographic process.

82. (New) The method of claim 80, wherein the cap layer cap layer also functions as a mask during the etching process.

83. (New) The method of claim 80, wherein an additional portion of the cap layer is etched while the cap layer protects the wiring line layer during the plasma based process.

84. (New) The method of claim 80, further comprising forming a surface layer between the substrate and the wiring line layer.

85. (New) The method of claim 80, further comprising the step of removing the cap layer before depositing a dielectric material within the gaps.

86. (New) The method of claim 80, wherein portions of the cap layer are removed and portions of the cap layer act as a mask during the etching of the first antireflective coating and the wiring line layer.

87. (New) The method of claim 80, wherein after etching each wiring line has a portion of the cap layer thereon, the portion of a cap layer on each wiring line having a cross-sectional shape selected from the group consisting of a rectangle, a triangle, trapezoid, and a rectangle having its upper corners etched away.

88. (New) The method of claim 80 wherein the cap layer and the first antireflective coating are used as a hard mask.

89. (New) The method of claim 80 wherein the cap layer and the first antireflective coating form a graded change in an index of refraction.

90. (New) The method of claim 80 wherein the cap layer has a dielectric constant that is closer than a dielectric constant of the first

antireflective coating to a subsequent photoresist mask layer dielectric constant.

91. (New) The method of claim 80, wherein the second plasma based process deposits material at a higher rate than the first plasma based process.

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92. (New) The method of claim 80, wherein the second plasma based process is a PECVD oxide process.

93. (New) The method of claim 80, wherein the cap layer comprises silicon, oxygen, and nitrogen.